

Atty Docket No. Serial No. U.S. Department of Commerce, Patent and Trademark Office M-10693 US Unknown INFORMATION DISCLOSURE STATEMENT BY APPLICANT Applicants: Steve Biellak, et al. (Use several sheets if necessary) Filing Date: June 26, 2001 Group: Unknown U.S. Patent Documents Filing Date *Examiner Document Number If Appropriate Initial Date Name Class Subclass 4,449,818 5/1984 Yamaguchi AA AB 4,794,265 12/1988 Quackenbos et al. AC 4,893,932 1/1990 Knollenberg AD 4,898,471 2/1990 Stonestrom et al. AE 4,929,845 5/1990 Amir et al. 10/1991 Katzir AF 5,058,982 2/1995 5,389,794 Allen et al. AG ΑH 5,424,838 6/1995 Siu ΑI 6/1996 Nikoonahad et al. 5,530,550 Yasutake et al. AJ 5,650,614 7/1997 AK 5,798,829 8/1998 Vaez-Iravani 5/1995 Gross et al. AL5,416,594 AM 6,201,601 B1 3/2001 Vaez-Iravani et al. 09/746,141 12/21/00 AN Foreign Patent Documents Translation Yes Document Date Country Class Subclass No X AO WO97/33158 9/1997 International AP EP0624787 11/1994 Europe X X AQ DE4123916 1/1992 German X AR WO97/12226 4/1997 International ART (Including Author, Title, Date, Pertinent Pages, Etc.) "Surface Inspection System for Estimation of Wafer," Y. Yatsugake et al., Hitachi Electronics AS Engineering Technical Report, Vol. 11, January 1996, pp. 21-26 Figure, Hitachi Electronics Engineering Co., Ltd., presented by Etsuro Morita of Mitsubishi Materials AT Silicon Corp. in a presentation entitled "Exploration of COP and COP Defect Crystal Originated 'Particles'," at the 6th International Workshop on 300 Millimeter Wafers on 12/5/1996 in Makuhari, Japan Partial European Search Report dated October 18, 2000 AU 22102 Examiner **Date Considered**

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